



AF/1746

IFW

PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/040,042 Confirmation No. 1835
Applicant : Wei-Yu Su
Filed : November 7, 2001
TC/A.U. : 1746
Title : Method for Reduction of Photomask Defects

Docket No. : N1085-90003
Customer No. : 08933

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING,
37 C.F.R. §1.8(a)

I certify that this correspondence and the
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Richard A. Paikoff
Richard A. Paikoff, Reg. No. 34,892

10/22/04
Date

AMENDMENT AND RESPONSE UNDER 37 CFR §116(a)

Do not enter
ZE 11/8/04

Sir:

In response to the Office Action of August 27, 2004, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.